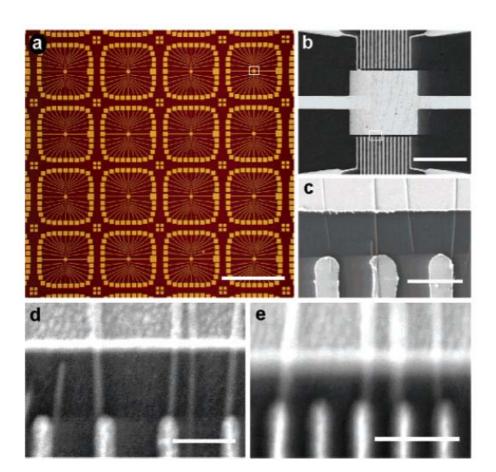
Semiconductor nanowires: 2 Electronic applications

11/10/2005

## Si naowire devices

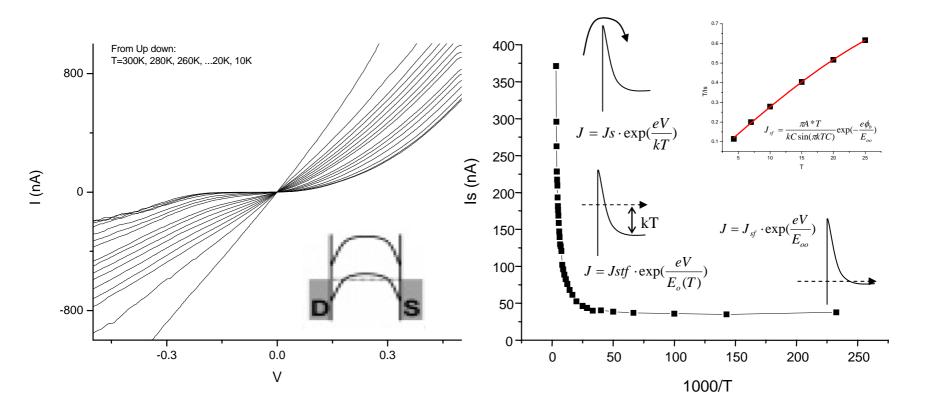


 $\mu$ ~300cm<sup>2</sup>/Vs uniform behavior

а 15 10 l<sub>sd</sub> (μA) 5 C -5 -10 V<sub>sd</sub>(V) -2 2 -4 4 b 10<sup>1</sup> 3 10<sup>-1</sup> l<sub>sd</sub> (μA) 10<sup>-3</sup> 10<sup>-5</sup> 10<sup>-7</sup> 04  $V_g^{(V)}$ -2.5 2.5 -5 5 С 10 10<sup>-1</sup> (M)<sup>ps</sup> 10<sup>-5</sup> Transconductance (nS) 10<sup>-7</sup> 0 V<sub>g</sub>(V) -5 -2.5 2.5 5

Jin, Nano Lett. 4, 915 (2004)

### Shottky barrier formation at the contacts

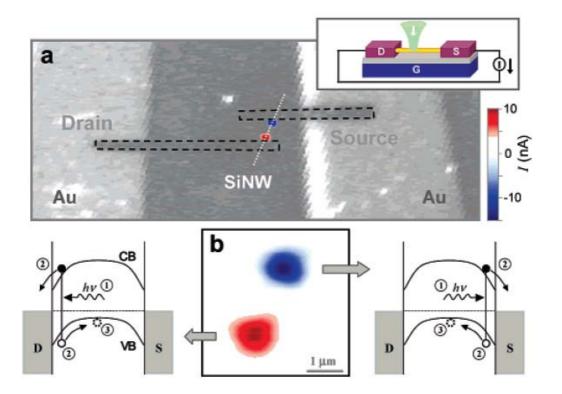


•Ohmic-like contact at RT because of thermally assisted tunneling and thermal emission

•Shottky barrier is obvious at low T.

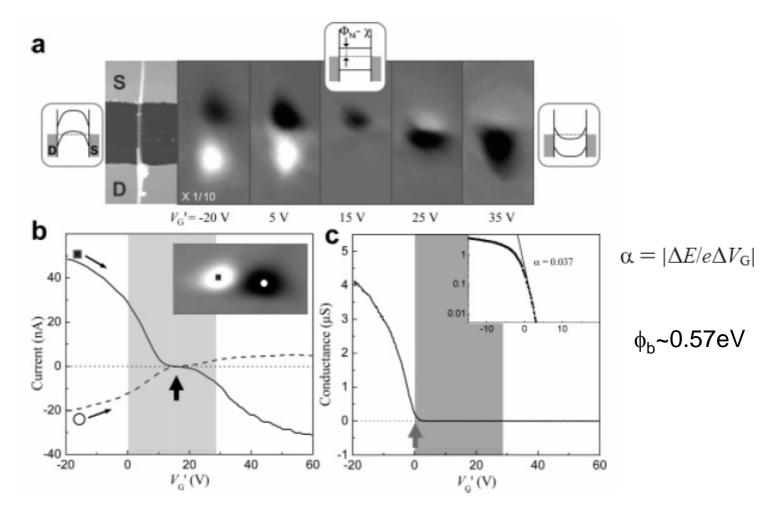
•Typical contact resistance ~  $100K\Omega$ - $1M\Omega$  per wire

## Measuring the Schottky barrier with photocurrent

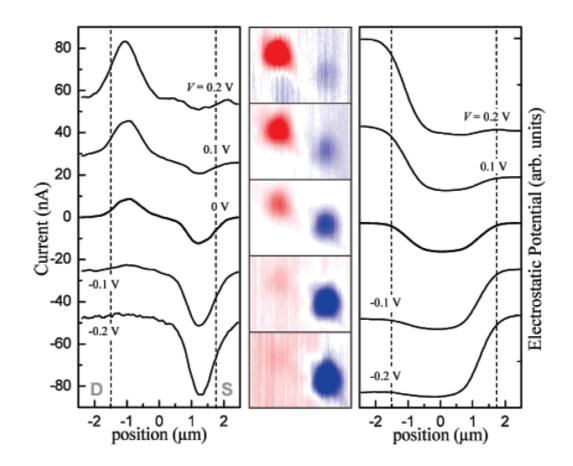


Ahn, Nano Lett, 5, 1367 (2005)

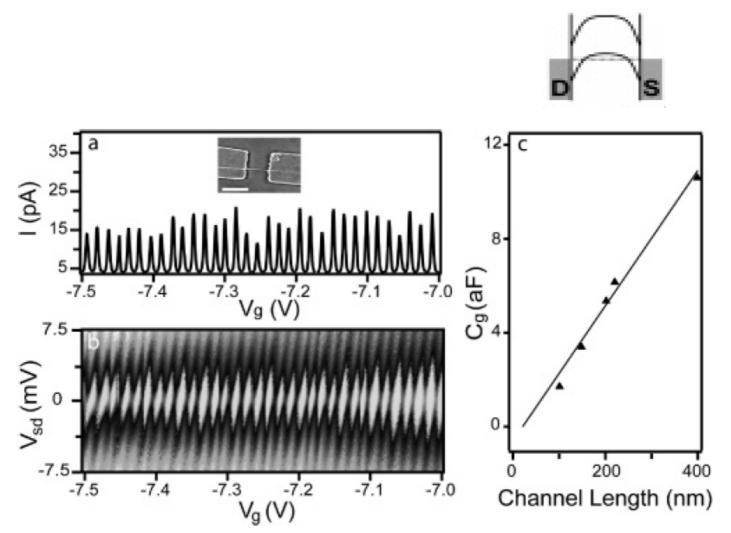
## Measuring the Schottky barrier with photocurrent



## Measuring the potential inside the channel with photocurrent

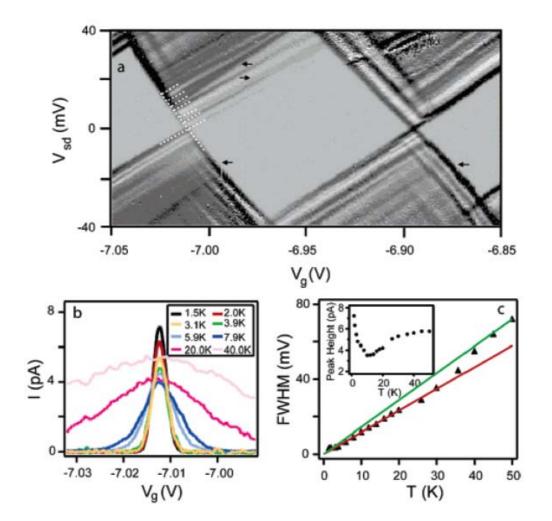


Schottky barrier formation at the source/drain contacts



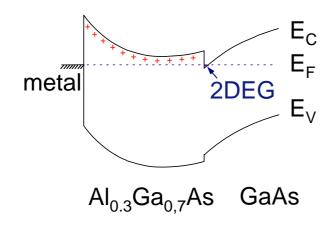
Zhong, Nano Lett, 5, 1143 (2005)

Schottky barriers as tunnel barriers Quantum dot formed between the source/drain electrodes Schottky barrier formation at the source/drain contacts



Zhong, Nano Lett, **5**, 1143 (2005)

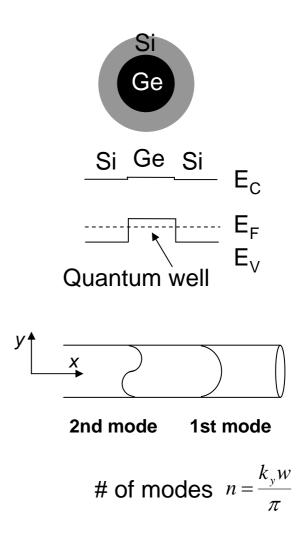
## Elimination of Schottky barriers and dopants



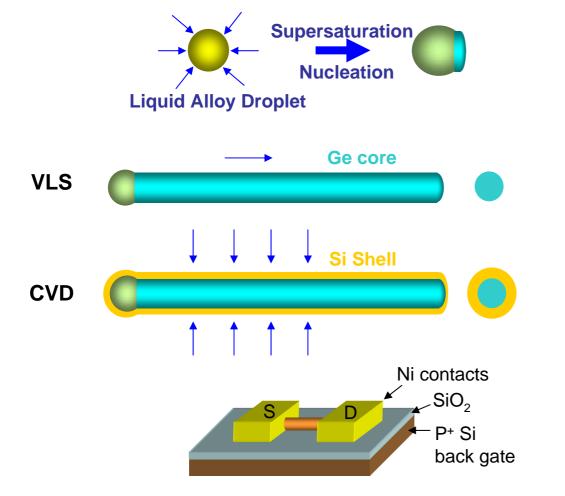
dopants - impurities Schottky barriers

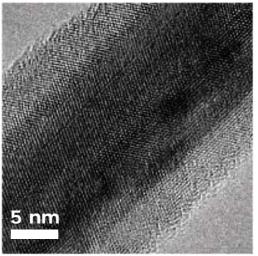
# Band structure engineering

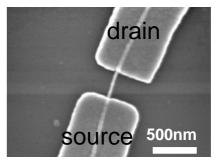
- •Carrier injection w/o dopants in the channel
- •Valence band offset between Ge and Si
- •Cylindrical confinement, quantum size effects



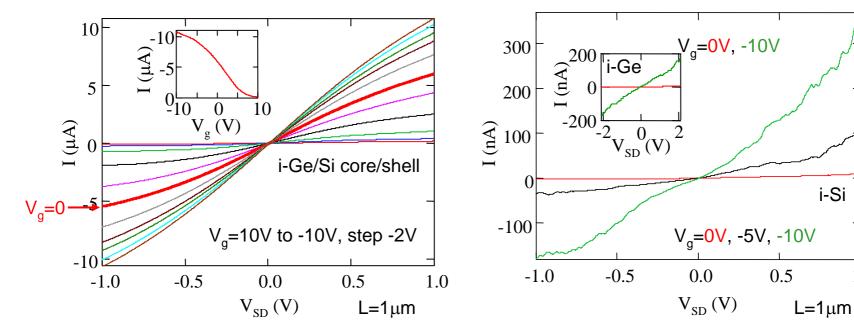
## Ge/Si core/shell nanowire growth



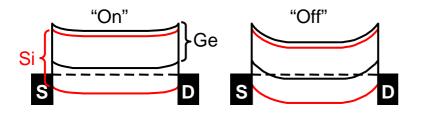




## Room-T transport studies

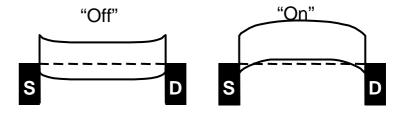


"Depletion mode"



contact doping

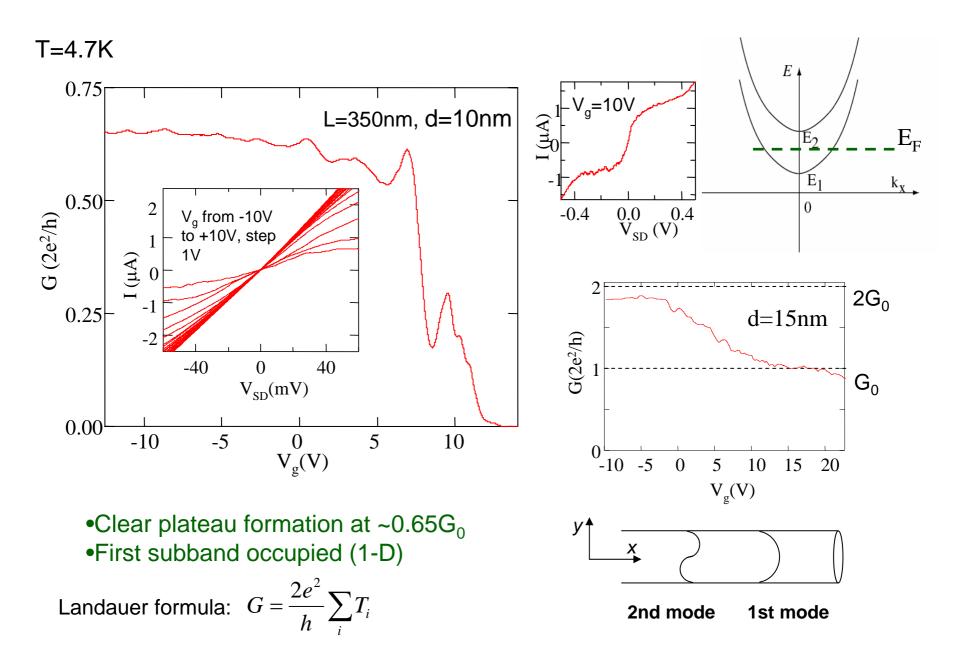
"Enhancement mode"



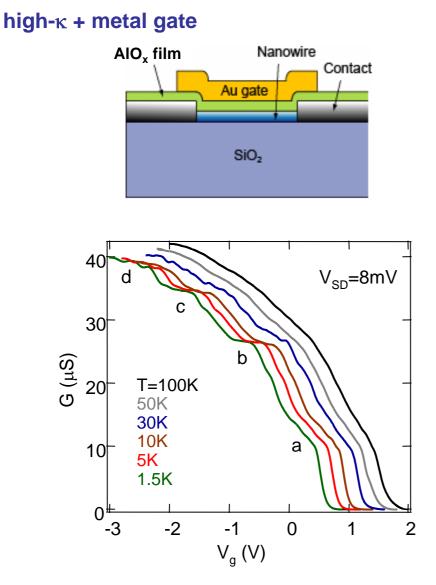
Schottky barrier formation

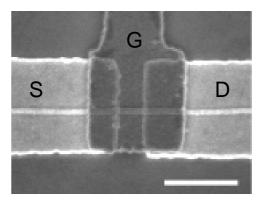
1.0

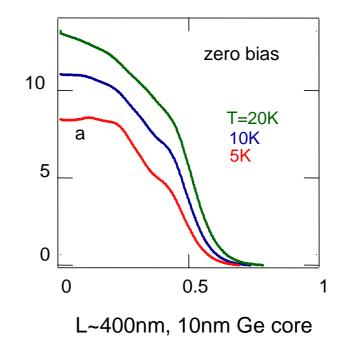
Low T- Conductance quantization



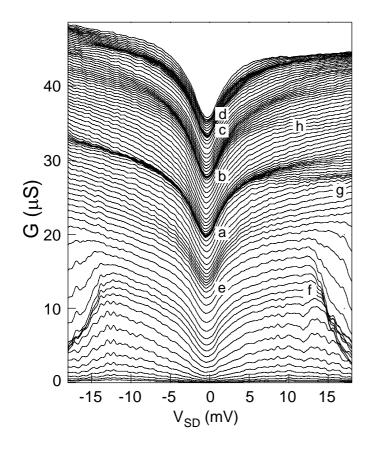
## Top gate, multiple 1D channels



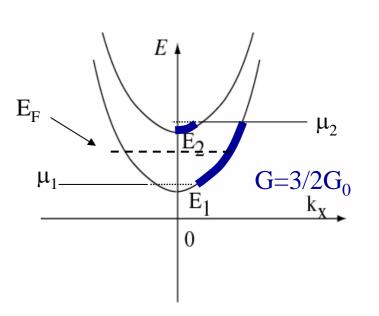




## Non-Equilibrium Studies, multiple subbands



series of  $\text{G-V}_{\text{SD}}$  in  $\text{V}_{\text{g}}$  steps of 50 mV no offset adjustment



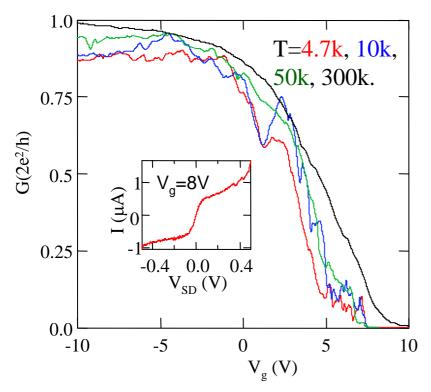
- plateaus —> accumulation of curves, a-d
- half-plateaus at higher biases, f-h
- cusp → small potential fluctuations inside the channel

## $dG/dV_{a}$ map, subband spacings

E<sub>2,3</sub>=30meV \_ E<sub>1,2</sub>=25meV  $dG/dV_{q}-V_{q}-V_{SD}$ 20 10 dG/dVg (µS/V) V<sub>SD</sub> (mV) -10 -20 V<sub>a</sub> (V)  $-\frac{\hbar^2}{2m}\nabla^2\varphi(\vec{r}) + V(\vec{r}) = E\varphi(\vec{r})$  $\nabla^2 = \frac{1}{r} \frac{\partial}{\partial r} \left( r \frac{\partial}{\partial r} \right) + \frac{1}{r^2} \frac{\partial^2}{\partial \theta^2} + \frac{\partial^2}{\partial z^2}$ E<sub>1,2</sub>~25meV E<sub>2.3</sub>~32meV  $E_{mi} = \frac{\hbar^2 {u_{mi}}^2}{2m^* a^2} + \frac{\hbar^2 k^2}{2m^*}$ for d=2a=14nm  $V(r) = \begin{cases} +\infty, r \ge a \\ 0, r \le a \end{cases}$  $u_{mi}$ : J<sub>m</sub>(x)'s *i*th zero point

## Temperature dependence

L=170nm



Acoustic phonon scattering rate at room T

Following Fermi's golden rule 
$$\frac{1}{\tau_{ap}} = \frac{\pi k_B T \Xi^2}{\hbar \rho v_s^2} D(E_F)$$
  
 $D(E) = \frac{\sqrt{2m^*}}{\pi \hbar \sqrt{E}} \frac{1}{\pi r^2}$  density of states in 3D form  
 $\rho$  mass density, 5.3 g/cm<sup>3</sup>  
 $\Xi$  deformation potential, 3.81 eV  
 $V_s$  velocity of sound, 5400 m/s

acoustic phonon scattering rate  $\tau_{ap} \sim 4.5 \times 10^{-12}$  s

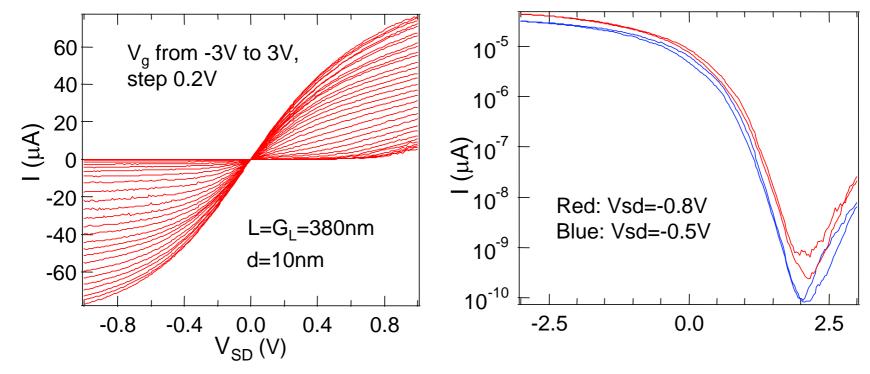
$$v_{\rm F} = \frac{\hbar k_{\rm F}}{m^*} \sim 1.1 \times 10^5 \,\mathrm{m/s}$$

mean free path 
$$l \sim 492$$
 nm

1

- •Little temperature dependence
- •Reduction of phonon scattering
- •Room temperature ballistic devices

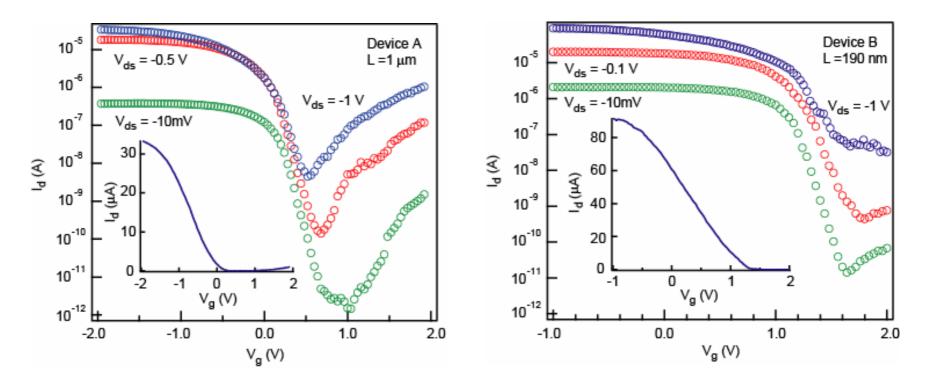
## Top gated Ge/Si nanowire devices, room T



With AIO<sub>x</sub> dielectric

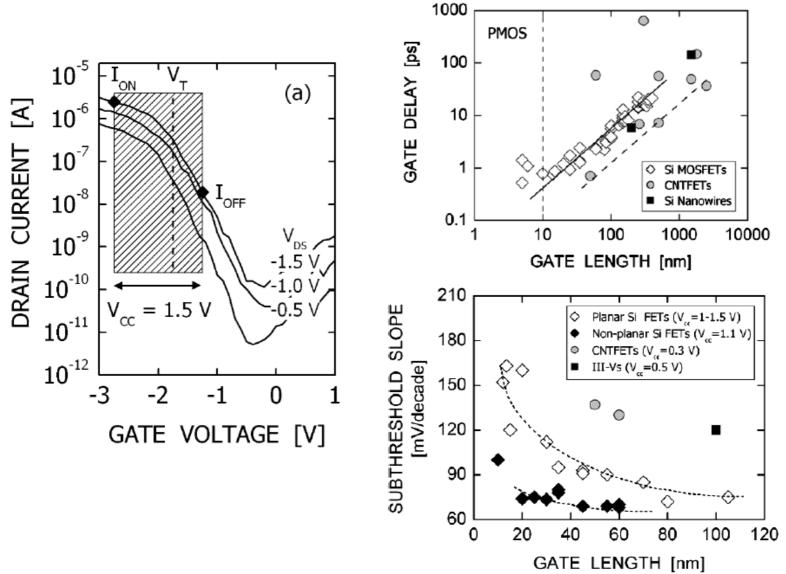
• $I_{on}$ > 70 μA • $G_m$ >20 μS, among highest achieved (~1mS/μm), at -1V •on/off > 10<sup>5</sup> •Uniform behavior (100% yield)

#### Top gated Ge/Si nanowire devices, room T

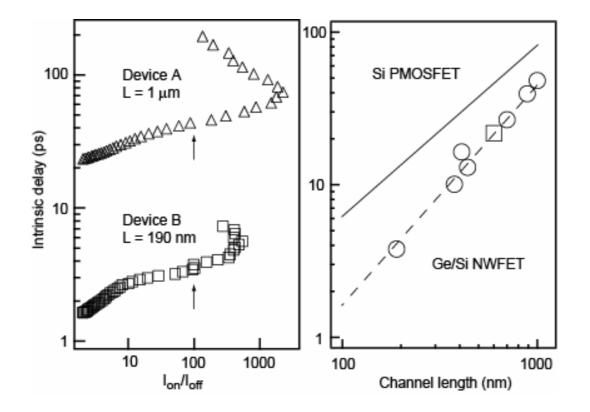


•3X improvements achieved using better high-k dielectrics (HfO<sub>2</sub>) •G<sub>m</sub>=3.3 mS/ $\mu$ m •I<sub>on</sub>=5 mA/ $\mu$ m •CV/I=3.8ps with V<sub>dd</sub>=1V

## Benchmarking of nanoFETs



## CV/I scaling of Ge/Si nanowires

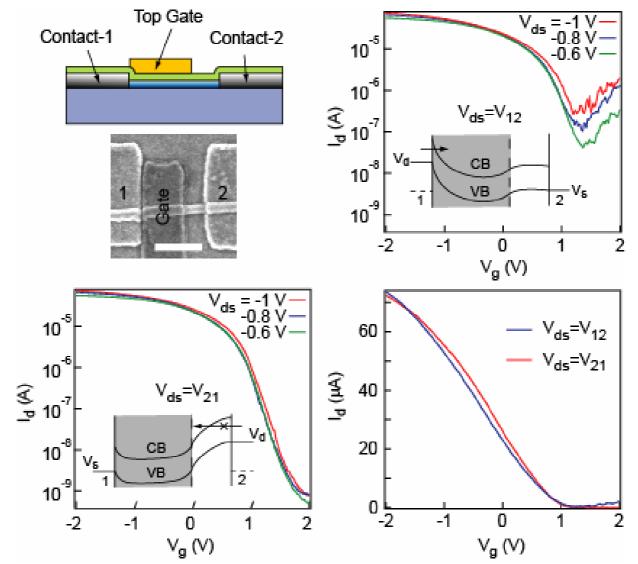


•CV/I data points picked at  $I_{on}/I_{off}$ =100

•Better than state-of-the-art p-Si devices

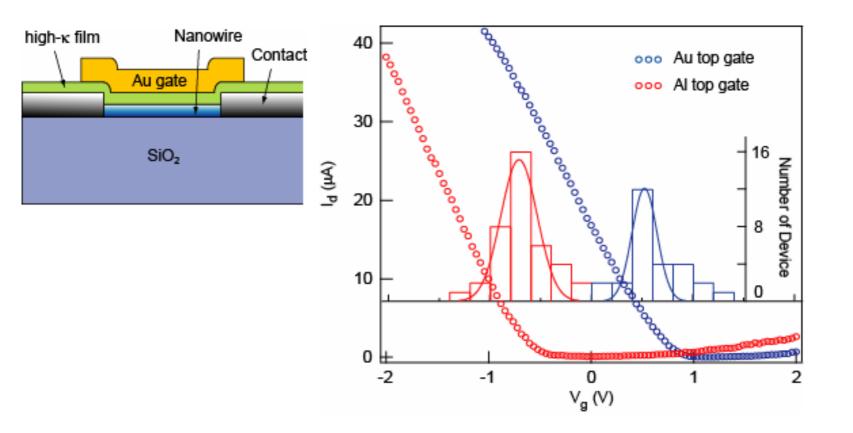
•Sharper slope obtained, due to suppression of mobility degradation.

## Ambipolar suppression



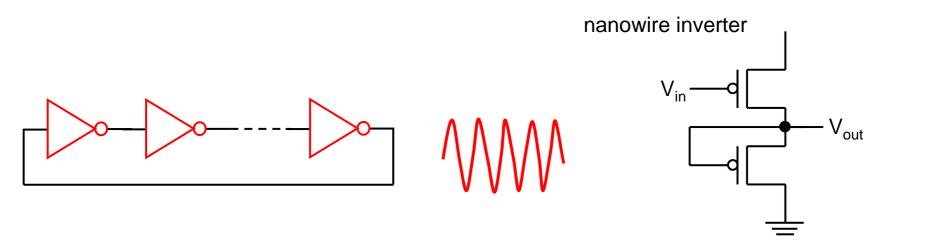
Metal contacts results in pronounced ambipolar behavior.Ungated region as local contacts instead.

# Threshold engineering



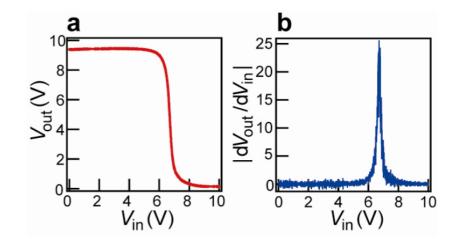
•Both depletion mode ( $V_T$ >0) and enhancement mode ( $V_T$ <0) devices can be obtained via selection of top gate materials. •High uniformity

## Nanowire ring oscillators



Ring oscillators:

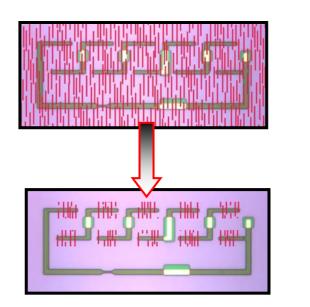
- Excellent circuit for demonstrating reliable integration
- Excellent circuit for demonstrating gain/driving capabilities
- Excellent circuit for demonstrating high freq performance/limitations
- "An oscillator of some sort is an essential ingredient in electronics"

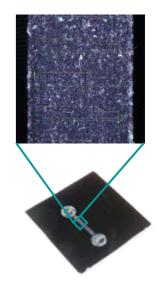


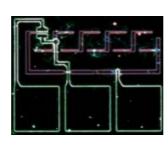
Si nanowire inverter response

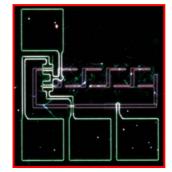
## Nanowire ring oscillators

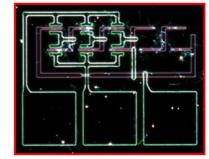
Deposit wires by flow-alignment and pattern via photolithography









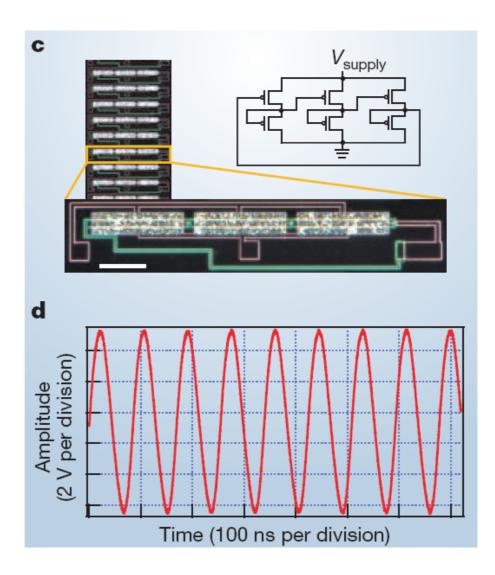


Uniformity critical in these multiple wire devices

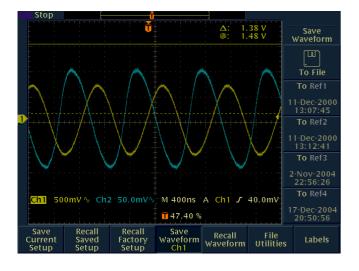
## Si nanowire ring oscillators

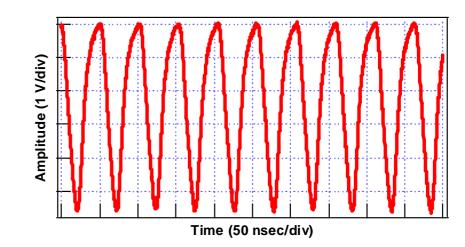
*f*>4MHz on oxidized Si substrate

*f*>10MHz on glass substrate



## Ge/Si nanowire ring oscillators





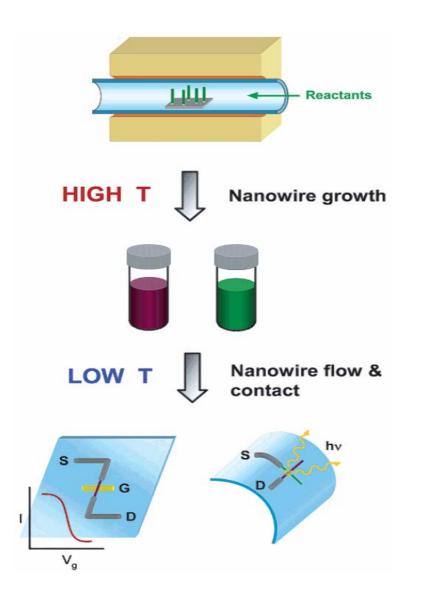
*f*~20MHz

Inverter response

Ring oscillator response

- Initial attempt on Si substrate already yields f~20MHz
- 3-4 times faster on insulating substrate, eg, glass
- Further optimization

## Nanowire devices on flexible substrates

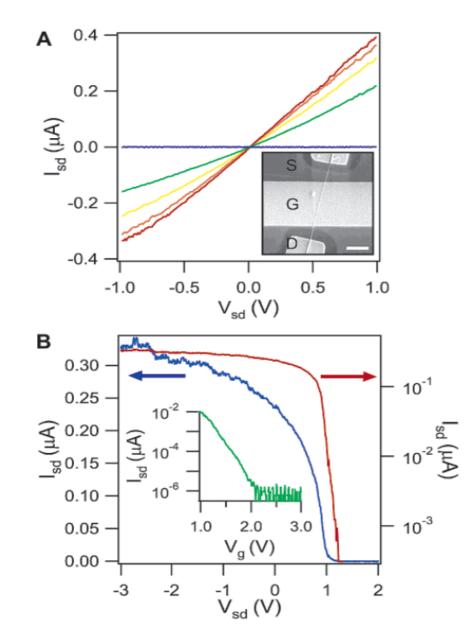


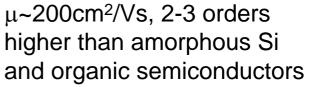
•Separation of high temperature material growth and low temperature device fabrication processes.

•High performance electronic and photonic devices on plastics

McAlpine, Nano Lett. 3, 1531 (2003)

#### Nanowire devices on flexible substrates

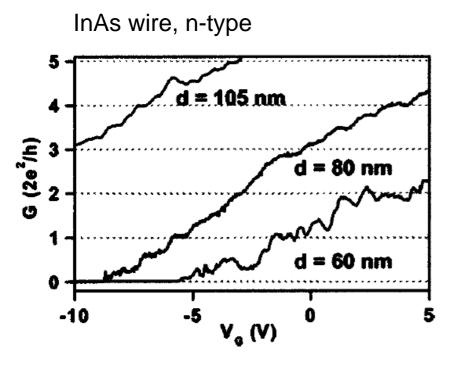




#### InAs nanowires and axial heterostructures

## Samuelson group, Lund Univ

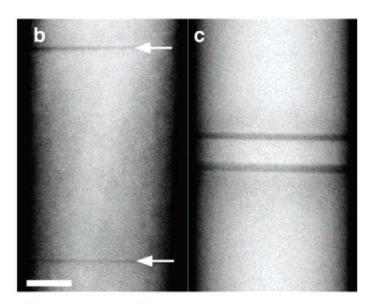
Bjork, Nano Lett 4, 1621 (2004)

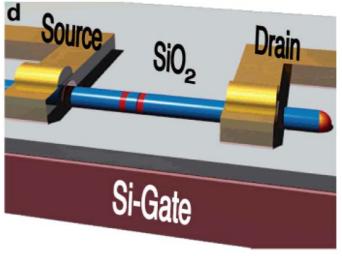


Thelander, APL, 83, 2052 (2003)

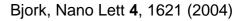
Diameter dependence of the threshold

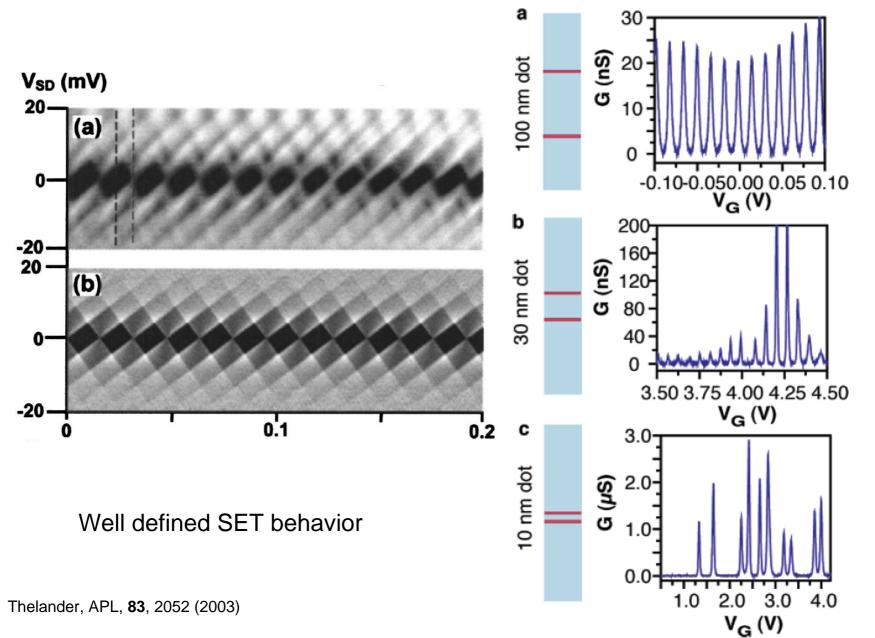
InAs wires with InP tunnel barriers Controlled growth via the CBE method

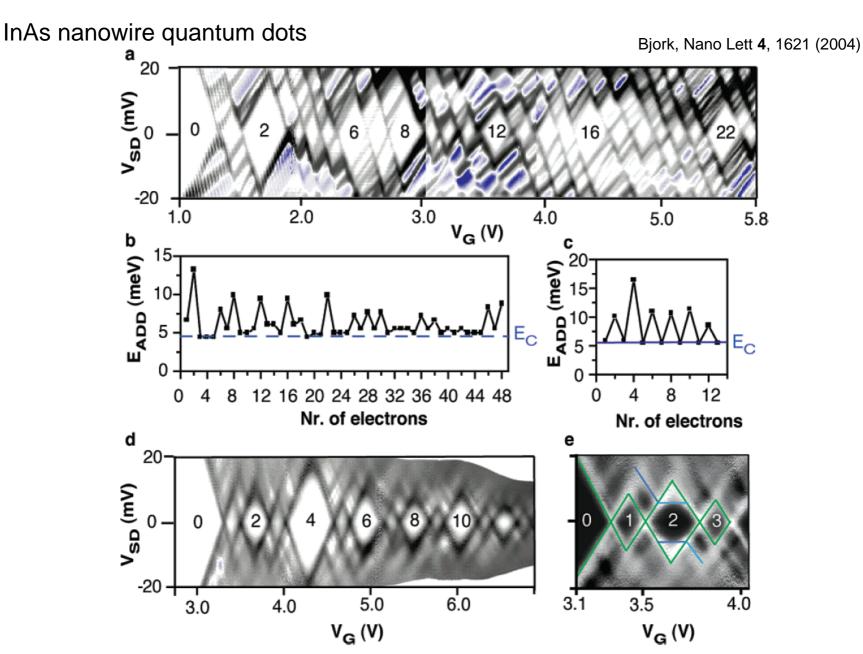




## Axial heterostructures, controlled growth of tunnel barriers







Few charge quantum dot obtained by reducing the dot size (separation of the InP barriers)

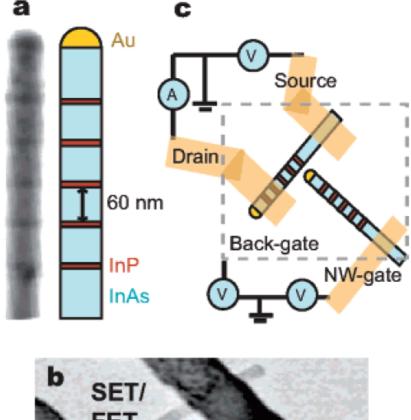
## Nanowire based single electron memory

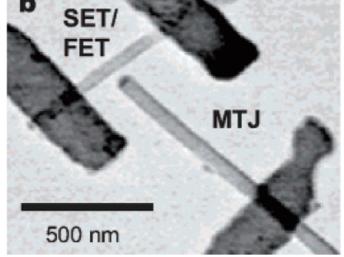
100 nm

 Individual electrons added/removed via tunneling through the InP barriers

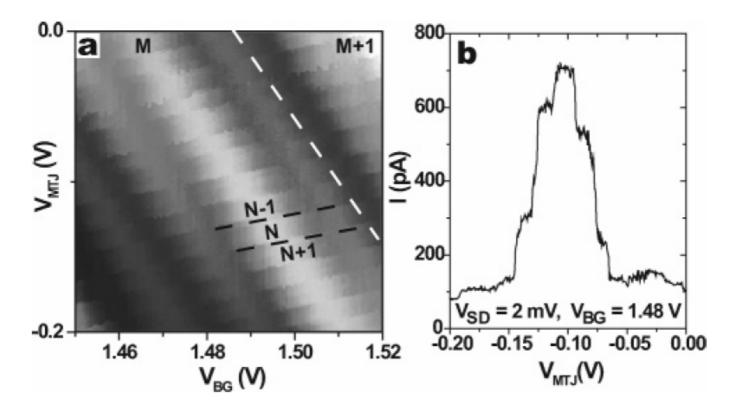
•Au nanoparticle as the charge storage node

•A second nanowire SET detects number of charges on the Au nanoparticle





#### Nanowire based single electron memory



N: number of electrons on the Au particle M: number of electrons on the SET T=4.2K

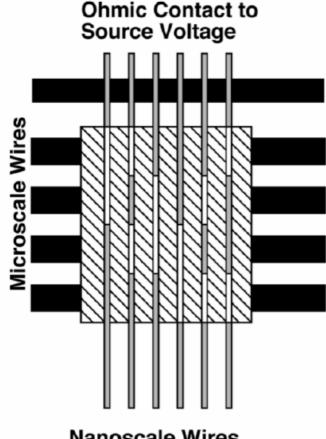
### Decoder: bridging the nanoscales wires with micro scale wires

Ohmic contact Ohmic Contact Vprog column/Vread to Source Voltage Vprog\_row/Vout CA0 Oxide (separate CA1 micro and Oxide nano) Oxide (separate nano CA2 (separate Vrdis and micro wires) micro and CA3 nano) Control Wires Modulationdoped decoders Nanowire device arrays Ohmic contac Ohmic cont FET control to disconnect or provide weak resistive pull Bit Positions to Vcol, Vrow 2 Vcdis RA2 RA3 RA0 RA1 Vcol 0 **Ohmic contact** 0 code

DeHon, IEEE Trans Nano, **2**, 165 (2003)

Coding achieved via modulation doping (gatable regions vs. ungatable regions) 2<sup>N</sup> nanowires can be addressed by N microwires with perfect registry

DeHon, IEEE Trans Nano, 2, 165 (2003)



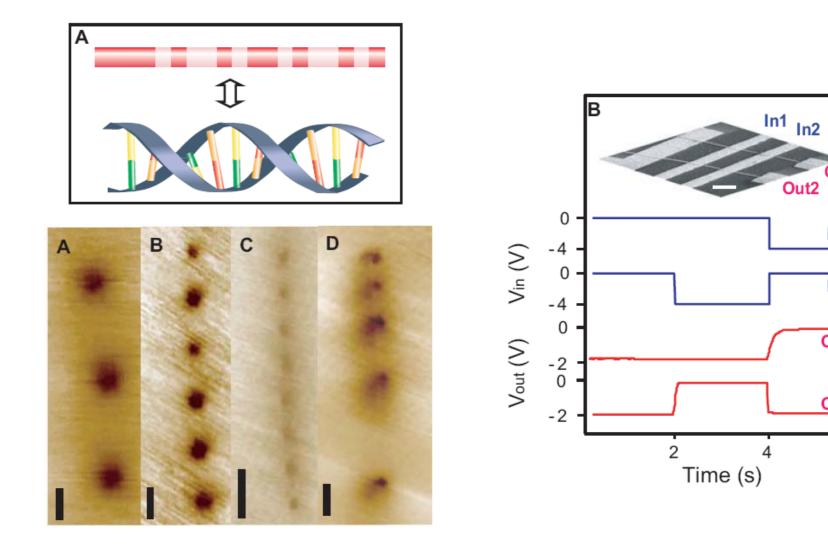
# PROBABILITY THAT ALL N WIRES IN A SET ARE UNIQUE WHEN SELECTED FROM CODES OF SIZE ${\cal C}$

Array Size	Code Size	Probability Estimates	
(N = u)	(C)	(Eq. 4)	(Eq. 3)
10	100	0.35	0.62
10	1,000	0.90	0.96
10	10,000	0.990	0.996
100	10,000	0.37	0.61
100	100,000	0.90	0.95
100	1,000,000	0.990	0.995
1000	1,000,000	0.37	0.61
1000	10,000,000	0.90	0.95
1000	100,000,000	0.990	0.995

Nanoscale Wires

Unique addressing of all N nanowires can be obtained via stochastic decoding with large coding spaces without registry

# Coding via modulation doping of Si nanowires



Out1

In1

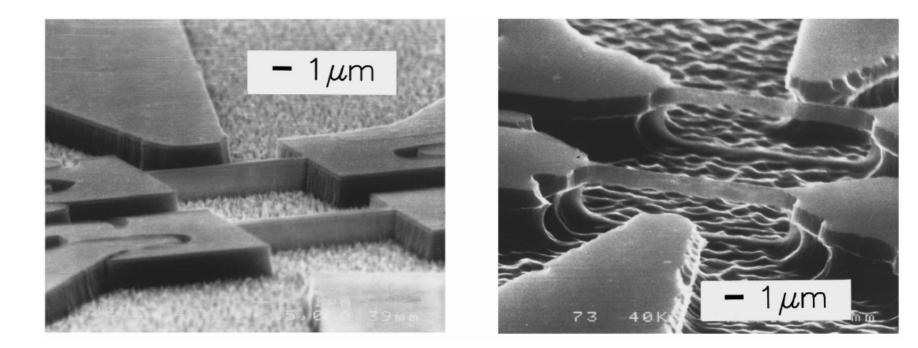
In2

Out1

Out2

## Mechanical resonators

Cleland, APL, 69, 2653 (1996)

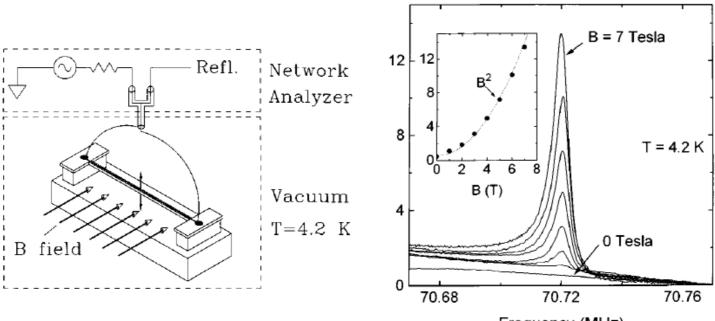


$$\omega = \left(\frac{4.73}{l}\right)^2 \left(\frac{EI}{\rho A}\right)^{1/2},$$

Application: passive RF filters, oscillators for wireless communications. (eg, prof. Nguyen's group).

Fundamental interest (flexural modes):  $hf\sim50$  mK for f=1GHz, quantum mechanical system.  $hf\sim4\mu$ eV, comparable to energy scales of electrical systems. Entangled mechanical/electrical systems.

#### Magnetomotive actuation



Frequency (MHz)

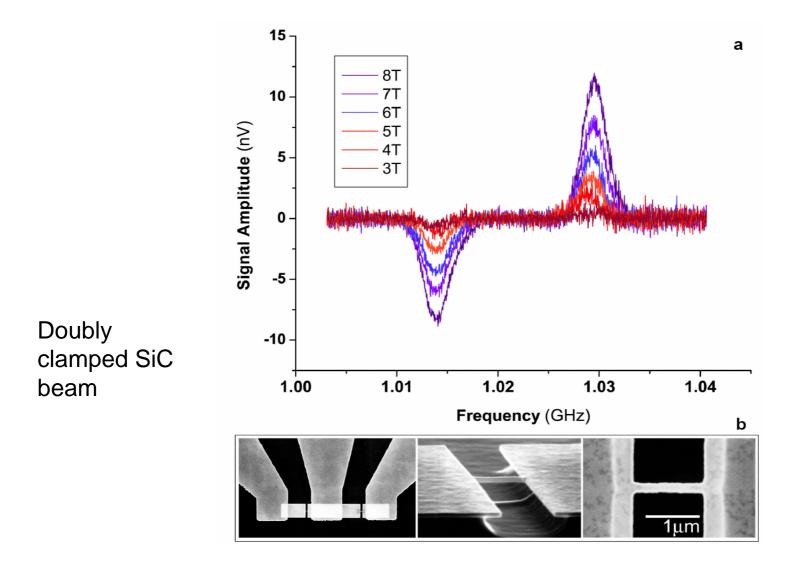
In plane magnetic field. AC current creats Lorentz driving force.

Other actuation methods

•Electromotive (AC signals applied to coupling electrodes, driven by electric forces)

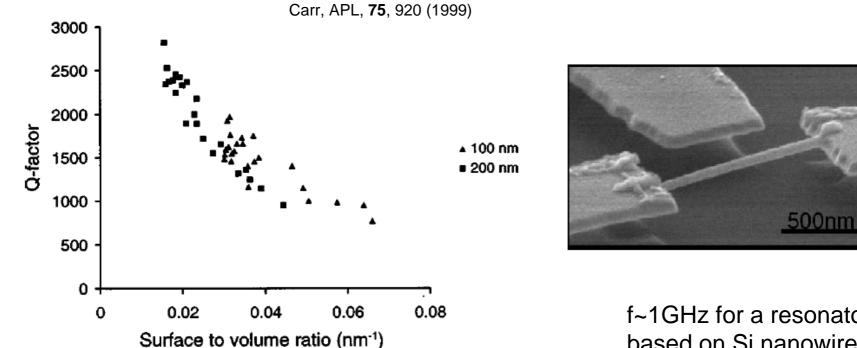
•Piezoelectric forces (AC bias causes mechanical driving force)

## GHz resonators



f~1GHz, Q~500

## Surface roughness induced losses



•For samples produced via the etching process, surface induced losses dominates the quality factor

•Such loss may be avoided in devices produced by single-crystalline nanowires.

•Piezoelectric actuation possible with (AIN) nanowires without magnetic fields and 3<sup>rd</sup> electrode

f~1GHz for a resonator based on Si nanowires with d=20nm and l=400nm.

## Comparing nanowires and nanotubes

#### Nanotubes:

#### Pros:

truly 1D system interesting properties (orbital degeneracy, electron-hole symmetry) Small diameter (~1-2nm) Large mean free path (~1 μm at low bias, 30 nm at high bias) High mobility (~3000\*d) (Zhou, PRL, **95**, 146805 (2005)

#### Cons:

Little control over metallic/semiconducting, chirality Hard to functionalize.

#### Nanowires:

#### Pros:

Uniformity (large scale application possible, devices on plastic substrates) Flexible (core/shell heterostructures, axial heterostructures) Heterostructure design greatly enhances mean free path and mobility Vertical FET with conformal gating? Can be easily functionalized for alignment and biosensing purposes Other applications (photonics, solar cells and gas sensing due to large surface area). High freq, high Q resonators?

#### Cons:

Larger size (~10-20 nm, but still small compared to top-down approach) Transport diffusive in most cases (may still be better than bulk materials due to confinement and smoother surface),